PATENT COOPERATION TREATY

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INTERNATIONAL PRELIMINARY REPORT ON PATENTABILITY

(Chapter II of the Patent Cooperation Treaty)

REC'D 0 1 SEP 2005

(PCT Article 36 and Rule 70)

WIPO PCT

Applicant's or agent's file reference 15992-WO-03+	FOR FURTHER ACTI	ON s	ee Form PCT/IPEA/416		
International application No. PCT/IL2004/000573	International filing date (day 28.06.2004	v/month/year)	Priority date (day/month/year) 02.07.2003		
International Patent Classification (IPC) or na H01L31/101	ational classification and IPC				
Applicant SEMI-CONDUCTOR DEVICES - AN ELBIT SYSTEMS					
Authority under Article 35 and trai	Authority under Article 35 and transmitted to the applicant according to Article 36.				
2. This REPORT consists of a total					
3. This report is also accompanied by	y ANNEXES, comprising:		6-10		
a. 🛛 sent to the applicant and t	o the International Bureau) a total of 6 sheets,	as follows:		
⊠ sheets of the description and/or sheets containion Administrative Instruc	and/or sheets containing rectifications authorized by this Authority (see Rule 70.16 and Section 607 of the				
sheets which supersede earlier sheets, but which this Authority considers contain an amendment that goes beyond the disclosure in the international application as filed, as indicated in item 4 of Box No. I and the Supplemental Box.					
b. (sent to the International I	b. (sent to the International Bureau only) a total of (indicate type and number of electronic carrier(s)), containing a				
Box Relating to Sequence	Box Relating to Sequence Listing (see Section 802 of the Administrative Instructions).				
4. This report contains indications r	elating to the following iter	ms:			
Box No. I Basis of the op	inion				
☐ Box No. II Priority			-t and industrial applicability		
4					
☐ Box No. IV Lack of unity o	f invention	with regard to povolty	inventive step or industrial		
applicability; c	Box No. V Reasoned statement under Article 35(2) with regard to novelty, inventive step or industrial applicability; citations and explanations supporting such statement				
☐ Box No. VI Certain docum					
☐ Box No. VIII Certain observ	Box No. VIII Certain observations on the international application				
Date of submission of the demand		Date of completion of th	ls report		
26.04.2005		02.09.2005			
Name and mailing address of the internati preliminary examining authority:		Authorized Officer	John Palenter		
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INTERNATIONAL PRELIMINARY REPORT ON PATENTABILITY

International application No. PCT/IL2004/000573

		No. I	Basis of the report
1.	With filed	l, unles:	d to the language, this report is based on the international application in the language in which it was so otherwise indicated under this item.
		This re	eport is based on translations from the original language into the following language, is the language of a translation furnished for the purposes of:
		☐ inte	ernational search (under Rules 12.3 and 23.1(b)) blication of the international application (under Rule 12.4) ernational preliminary examination (under Rules 55.2 and/or 55.3)
2.	hai	a haan	ed to the elements * of the international application, this report is based on (replacement sheets which In furnished to the receiving Office in response to an invitation under Article 14 are referred to in this "originally filed" and are not annexed to this report):
	Des	scriptio	n, Pages
	1-3	-	as originally filed
	Cla	ims, Nu	•
	1-3	1	filed with telefax on 26.04.2005
	Dra	awings,	Sheets
	1/1	6-16/16	as originally filed
		a seq	quence listing and/or any related table(s) - see Supplemental Box Relating to Sequence Listing
3.		The a	amendments have resulted in the cancellation of:
		☐ th	ne description, pages ne claims, Nos.
		☐ th	ne drawings, sheets/figs
		☐ th	ne sequence listing <i>(specify)</i> : ny table(s) related to sequence listing <i>(specify)</i> :
4	. 🗆		report has been established as if (some of) the amendments annexed to this report and listed below been made, since they have been considered to go beyond the disclosure as filed, as indicated in the
	Si	upplem	ental Box (Rule 70.2(c)).
			ne description, pages ne claims, Nos.
		□ tt	he drawings, sheets/figs
		□а	he sequence listing <i>(specify)</i> : ny table(s) related to sequence listing <i>(specify)</i> :
	*	If :	item 4 applies, some or all of these sheets may be marked "superseded."

INTERNATIONAL PRELIMINARY REPORT ON PATENTABILITY

International application No. PCT/IL2004/000573

Box No. V Reasoned statement under Article 35(2) with regard to novelty, inventive step or industrial applicability; citations and explanations supporting such statement

1	Stat	e	m	ei	٦t
				v	

Novelty (N)	 Claims Claims	1-31
Inventive step (IS)	 Claims Claims	1-31
Industrial applicability (IA)	 Claims Claims	1-31

2. Citations and explanations (Rule 70.7):

see separate sheet

INTERNATIONAL PRELIMINARY REPORT ON PATENTABILITY (SEPARATE SHEET)

PCT/IL2004/000573

Reference is made to the following documents:

D1: PARK J ET AL: "Reduction of dark current in an n-type In0.3Ga0.7As/GaAs quantum well infrared photodetector by using a camel diode structure" SOLID STATE ELECTRONICS, ELSEVIER SCIENCE PUBLISHERS, BARKING, GB, vol. 46, no. 5, May 2002 (2002-05), pages 651-654, XP004346693 ISSN: 0038-1101

D2: US-A-4 740 819 (KAWATA MASAHIKO ET AL) 26 April 1988 (1988-04-26)

The application does not meet the requirements of Article 6 PCT, because claim 1 is not clear. The expression "when biased with an externally applied voltage, the bands in the photon absorbing layer next to the barrier layer...." discloses a condition that stems from the way the photodetector is operated and not from its intrinsic properties, hence the subject-matter for which protection is sought appears to be unclear.

The above objection notwithstanding, the subject-matter of claim 1 specifies that the bands in the photon absorbing layer next to the barrier layer are flat or accumulated, and the flat part of the valence band edge of the photon adsorbing layer lies below the flat part of the valence band edge of the contact layer and it also lies an energy of no more than 10KTop above the valence band edge in any part of the barrier layer. This feature is neither known nor rendered obvious by the disclosures of the closest prior art, D1 and D2. Hence the subject matter of claim 1 appears to be novel and inventive in the sense of Art. 33(2)(3) PCT.

The subject-matter of claims 2-12, is directly or indirectly dependent upon claim 1 and consequently is also novel and inventive in the sense of Art. 33(2)(3) PCT.

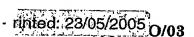
The subject-matter of claims 13-31 discloses either essentially the same subject-matter of claims 1-12 or straightforward applications of the device of claim 1, and consequently appears to be also novel and inventive.

INTERNATIONAL PRELIMINARY REPORT ON PATENTABILITY (SEPARATE SHEET)

International application No.

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CLAIMS

- 1. A photo-detector with a reduced G-R noise, comprising a sequence of a p-type contact layer, a middle barrier layer and an n-type photon absorbing layer, said middle barrier layer having an energy bandgap at least twice that of the photon absorbing layer, there being no layer with a narrower energy bandgap than that in the photon absorbing layer, wherein under flat band conditions the valence band edge of the contact layer lies below its own conduction band edge, or below the conduction band edge of the barrier layer, by at least twice the bandgap energy of the photon absorbing layer and, wherein when biased with an externally applied voltage, the bands in the photon absorbing layer next to the barrier layer are flat or accumulated, and the flat part of the valence band edge of the photon absorbing layer lies below the flat part of the valence band edge of the contact layer and it also lies an energy of not more than 10kTop above the valence band edge in any part of the barrier layer, where k is the Boltzman constant and Top is the operating temperature.
- 2. A photo-detector according to claim 1 wherein the photon absorbing layer has a typical thickness of 1-10 μ and doping of n <10¹⁶ cm⁻³.
- 3. A photo-detector according to claim 1 wherein the middle barrier layer has a thickness of between 0.05 and 1μm.
- 4. A photo-detector according to claim 1 wherein the barrier layer is doped n-type, typically $n < 5 \times 10^{16}$ cm⁻³, and a p-n junction is formed between said barrier layer and a p-type, $p < 5 \times 10^{18}$ cm⁻³, contact layer.
- 5. A photo-detector according to claim 1 wherein the barrier layer is doped p-type, typically $p < 5 \times 10^{16}$ cm⁻³ and a p-n junction is formed between said barrier

- layer and an n-type δ -doping layer typically with $5\times10^{10} < n < 10^{12}$ donors cm⁻² included at the edge of the photon absorbing layer next to the barrier layer.
- 6. A photo-detector according to claim 1 wherein the barrier layer is low-doped p-type, typically $p < 10^{15}$ cm⁻³, and a p-n junction is formed between said barrier layer and the n-type photon absorbing layer.
- 7. A photo-detector according to claim 1, wherein the photon absorbing layer is an InAs_{1-x}Sb_x alloy.
- 8. A photo-detector according to claim 1 wherein the photon absorbing layer is a type II superlattice material which comprises alternating sub-layers of InAs_{1-w}Sb_w and Ga_{1-x-y}In_xAl_ySb_{1-z}As_z with $0 \le w \le 1$, $0 \le x \le 1$, $0 \le y \le 1$, $0 \le z \le 1$ and x + y < 1 and wherein the sub-layers each have a thickness in the range of 0.6-10 nm.
- 9. A photo-detector according to claim 1 wherein the contact layer is GaSb.
- 10. A photo-detector according to claim 1, wherein the contact layer is a type II superlattice comprising alternating sub-layers of InAs_{1-w}Sb_w and Ga_{1-x-y}In_xAl_ySb_{1-z}As_z with $0 \le w \le 1$, $0 \le x \le 1$, $0 \le y \le 1$, $0 \le z \le 1$ and x + y < 1 and wherein the sub-layers have a thickness in the range of 0.6-10 nm.
- 11. A photo-detector according to claim 1 wherein the middle barrier layer is a Ga₁. $_{x}Al_{x}Sb_{1-y}As_{y}$ alloy with $0 \le x \le 1$ and $0 \le y \le 1$.
- 12. A photo-detector according to claim 1 in which the n-type photon absorbing layer is terminated by a highly n-doped terminating layer, typically with 3 × $10^{17} < n < 3 \times 10^{18}$ donors cm⁻³, and with thickness 0.5 4 μ , so that the valence band edge of said highly n-doped terminating layer lies below that of the n-type photon absorbing layer.

- 13. A photo-detector comprising stacked detector sub-units as in claim 7 or claim
 12 in which each detector sub-unit may have a different cut-off wavelength and
 in which each detector sub-unit is separated from its neighboring sub-unit by a
 p-type GaSb layer to which an external contact may be made.
- 14. A photo-detector with a reduced G-R noise, comprising a sequence of a p-type contact layer, a middle barrier layer and an n-type photon absorbing layer, said middle barrier layer having an energy bandgap significantly larger than that of the photon absorbing layer, there being no layer with a narrower energy bandgap than that in the photon-absorbing layer, wherein under flat band conditions the valence band edge of the contact layer lies below its own conduction band edge, or below the conduction band edge of the barrier layer, by significantly more than the bandgap energy of the photon absorbing layer and, wherein when biased with an externally applied voltage, the bands in the photon absorbing layer next to the barrier layer are flat or accumulated, and the flat part of the valence band edge of the photon absorbing layer lies below the flat part of the valence band edge of the contact layer and it also lies an energy of not more than $10kT_{0p}$ above the valence band edge in any part of the barrier layer, where k is the Boltzman constant and T_{0p} is the operating temperature.
- 15. A photo-detector according to claim 14 wherein the photon absorbing layer has a typical thickness of 1-10 μ and doping of n <10¹⁶ cm⁻³.
- 16. A photo-detector according to claim 14 wherein the middle barrier layer has a thickness of between 0.05 and $1\mu m$.

- 17. A photo-detector according to claim 14 wherein the barrier layer is doped n-type, typically $n < 5 \times 10^{16}$ cm⁻³, and a p-n junction is formed between said barrier layer and a p-type, $p < 5 \times 10^{18}$ cm⁻³, contact layer.
- 18. A photo-detector according to claim 14 wherein the barrier layer is doped p-type, typically $p < 5 \times 10^{16}$ cm⁻³ and a p-n junction is formed between said barrier layer and an n-type δ -doping layer typically with $5\times10^{10} < n < 10^{12}$ donors cm⁻², included at the edge of the photon absorbing layer next to the barrier layer.
- 19. A photo-detector according to claim 14, wherein the photon absorbing layer is InSb or an In_{1-x}Al_xSb alloy.
- 20. A photo-detector according to claim 14 wherein the contact layer is InSb or an $In_{1-x}Al_xSb$ alloy.
- 21. A photo-detector according to claim 14 wherein the middle barrier layer is an In_{1-x}Al_xSb alloy.
- 22. A photo-detector according to claim 14 in which the n-type photon absorbing layer is terminated by a highly n-doped terminating layer, typically with $3 \times 10^{17} < n < 3 \times 10^{18}$ donors cm⁻³, and with thickness $0.5 4\mu$, so that the valence band edge of said highly n-doped terminating layer lies below that of the n-type photon absorbing layer.
- 23. A photo-detector with a reduced G-R noise, comprising a sequence of a n-type contact layer, a middle barrier layer and a p-type photon absorbing layer, said middle barrier layer having an energy bandgap significantly more than and preferably at least twice that of the photon absorbing layer, there being no layer with a narrower energy bandgap than that in the photon-absorbing layer,

wherein under flat band conditions the conduction band edge of the contact layer lies above its own valence band edge or above the valence band edge of the barrier layer by significantly more than and preferably at least twice the bandgap energy of the photon absorbing layer and, wherein when biased with an externally applied voltage, the bands in the photon absorbing layer next to the barrier layer are flat or accumulated, and the flat part of the conduction band edge of the photon absorbing layer lies above the flat part of the conduction band edge of the contact layer and it also lies an energy of not more than $10kT_{\rm op}$ below the conduction band edge in any part of the barrier layer, where k is the Boltzman constant and $T_{\rm op}$ is the operating temperature.

- 24. A photo-detector according to claim 23 wherein the photon absorbing layer has a typical thickness of 1-10 μ and doping of p <10¹⁶ cm⁻³
- 25. A photo-detector according to claim 23 wherein the barrier layer is doped p-type, typically $p < 5 \times 10^{16}$ cm⁻³, and a p-n junction is formed between said barrier layer and a n-type, $n < 5 \times 10^{18}$ cm⁻³, contact layer.
- 26. A photo-detector according to claim 23 wherein the barrier layer is doped n-type, typically $n < 5 \times 10^{16}$ cm⁻³ and a p-n junction is formed between said barrier layer and a p-type δ -doping layer typically with $5\times10^{10} acceptors cm⁻², included at the edge of the photon absorbing layer next to the barrier layer.$
- 27. A photo-detector according to claim 23 wherein the barrier layer is low-doped n-type, typically $n < 10^{15}$ cm⁻³, and a p-n junction is formed between said barrier layer and the p-type photon absorbing layer.

- 28. A photo-detector according to claim 23 in which the p-type photon absorbing layer is terminated by a highly p-doped terminating layer, typically with $3 \times 10^{17} acceptors cm⁻³, and with thickness 0.5 4<math>\mu$, so that the conduction band edge of the highly p-doped terminating layer lies above that of the p-type photon absorbing layer
- 29. A photo-detector comprising stacked detector sub-units as in claim 1, claim 14, claim 23 or a combination thereof, in which each detector sub-unit may have a different cut-off wavelength.
- 30. An array of identical detectors in which each detector is as in claim 1 or as in claim 14, or as in claim 23 and is connected to a silicon readout circuit by an indium bump.
- 31. An array of identical detectors in which each detector may be sensitive to more than one wavelength band as in claim 13, or as in claim 29, and in which each detector is connected to a silicon readout circuit using one indium bump or using one indium bump per detector sub-unit.